



Japan Gases & Facilities Committee Meeting Summary and Minutes

SEMICON Japan 2013 Wednesday, December 4, 2013, 14:30-16:00 Makuhari Messe, Chiba, Japan

Next Committee Meeting

SEMI Japan Standards Spring 2014 Meetings Friday, April 4, 2014, 15:00-17:00 SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs: Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan) **SEMI Staff:** Naoko Tejima (SEMI Japan)

Company	Last	First	Company	Last	First
Hitachi High Technologies	Enami	Hiromichi	Tokyo Electron Yamanashi	Moriya	Shuji
Swagelok	Ishida	Noritsugu	Tokyo Electron Tohoku	Okabe	Tsuneyuki
Flow Techno Service	Ishihara	Seiji	HORIBA STEC	Shimizu	Tetsuo
HORIBA STEC	Isobe	Yasuhiro	Tohoku University	Shirai	Yasuyuki
ITW Japan	Kashiwazaki	Hokuto	MKS Japan	Suzuki	Isao
Fujikin	Machii	Yoshifumi	SEMI Japan	Naoko	Tejima
ACE	Mihira	Hiroshi			

* alphabetical order by last name

Table 2 Leadership Changes

None

Table 3 Ballot Results

None

Table 4 Authorized Ballots

None

Table 5 Authorized Activities





Table 6 New Action Items

Item #	Assigned to	Details
G+F130927-01	SEMI staff	To prepare SNARF and SEMI F80 Reapproval ballot for Cycle 1, 2014.
G+F131204-01	NA Surface Mount Sandwich Component Dimensions TF	To send some information about Doc. 5596, "New Standard: Guide for the Development of Dimensional Standards for "Sandwich" Surface Mount Components", if they have.
G+F131204-02	Standardization of Live Gas Flow Rate SG	To make the meeting minutes and send it to the NA Committee.
G+F130927-03	Standardization of Live Gas Flow Rate SG	To resurvey about calibration of Live Gas Flow Rate will be made to Mass Flow Manufacturers, focusing on the item which could be candidates to be standardized.
G+F131204-04	Standardization of Live Gas Flow Rate SG	To ask some comments and opinions to be standardized the specific heat value to NA Gas Specification TF and Europe Gases & Liquid Chemicals Committee.

1 Welcome, Reminders and Introductions

Isao Suzuki, committee co-chair, called the meeting to order at 14:30. Self-introductions were made followed by the agenda review.

2 Technical Committee Award

Technical Committee Awards were given to the below members to appreciate their outstanding efforts and leadership.

• Shuji Moriya (Tokyo Electron)

3 Required Meeting Elements

The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Naoko Tejima.

4 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on September 27, 2013.

Motion:	To approve the minutes of the previous meeting, on condition of correcting the next meeting date (Year).			
By / 2 nd :	Hiroshi Mihira (ACE) / Seiji Ishihara, (Flow Techno Service)			
Discussion:	None			
Vote:	10 in favor and 0 opposed. Motion passed.			
Attachment:	01_JA_G+F_Previous_Mtg_Minutes_131204			

5 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2013 Calendar of Events, Global Standards Meeting Schedule, Critical Dates for SEMI Standards Ballots, SEMI Standards Publication, A&R Ballot Review Report, SEMICON Japan 2013 Information, SEMI Standards Meetings and Programs during SEMICON Japan 2013, SEMI Japan Standards Award and Contact Information.

Attachment: 02_SEMI_Staff_Report_131204





6 Liaison Reports

6.1 North America Facilities and Gases Committee

Kevin Nguyen briefly reported for the North America Facilities and Gases Committee. This report included Leadership, Current Committee Organization, Meeting Information, Leadership Change, New SNARFs, Ballot Results Summary, Upcoming Ballots for Cycle 1 & 2, 2014, Task Force Reports and Contact Information. Of note:

• Q) Regarding *Doc. 5596, "New Standard: Guide for the Development of Dimensional Standards for "Sandwich" Surface Mount Components*", JA members are not very familiar with the activities of "Sandwich" Surface Mount Components. Are there some materials can be shown?

A) There are only TFOF and SNARF at the current moment.

TFOF:

http://downloads.semi.org/web/wstdsbal.nsf/b8865 fa87d9e7b57882579 fb005c3cd7/6477d2b9a98 fdad088257b5c0067 f1dd! Open Document

SNARF:

http://downloads.semi.org/web/wstdsbal.nsf/b8865fa87d9e7b57882579fb005c3cd7/72ff8a145e42c1a988257b5c0068372e!OpenDocument

• Kevin Nguyen requested to share the meeting minutes of the Standardization of Live Gas Flow Rate Study Group to JA committee, since NA members are very interested in this topic.

Action Item: NA Surface Mount Sandwich Component Dimensions TF to send some information about Doc. 5596, "New Standard: Guide for the Development of Dimensional Standards for "Sandwich" Surface Mount Components", if they have.

Action Item: Standardization of Live Gas Flow Rate SG to make the meeting minutes and send it to the NA Committee.

Attachment: 03_NA_Facilities_and_Gases_Comm_Report_131204

6.2 Europe Gases and Liquid Chemicals Committee

Naoko Tejima briefly reported for the Europe Gases & Liquid Chemicals Committee. This report included Leadership, Current Committee Organization, Meeting Information, Ballot Results from Oct 2013 TC Meeting, New SNARFs from Oct 2013 TC Meeting, Existing SNARFs, Upcoming Ballots for 2014 and Task Force Reports.

Attachment: 04_EU_Gases_&_Liquid_Chemicals_Report_131204

6.3 Korea Facilities Committee

No report was provided.

7 Task Force Reports

7.1 Fl Revision Task Force

Yoshifumi Machii reported for the F1 Revision Task Force that there were not particular activities.

7.2 Gas Panel and Metal Seal Test Methods Task Force

Shuji Moriya reported for the Gas Panel and Metal Seal Test Methods Task Force that there were not particular activities.

7.3 5-year-review Task Force

Yoshifumi Machii reported for the 5-year-review Task Force. Of note:

• SEMI F80-0309, Test Method for Determination of Gas Change/Purge Efficiency of Gas Delivery System is due for 5year-review, and the submission of SEMI F80-0309 Reapproval ballot for Cycle 1, 2014 was approved at the previous committee meeting.

Action Item: SEMI staff to prepare SNARF and SEMI F80 Reapproval ballot for Cycle 1, 2014.





7.4 Standardization of Live Gas Flow Rate Study Group

Shuji Moriya reported for the Standardization of Live Gas Flow Rate Study Group. The Study Group met earlier in the day. Of note:

- Shared and discussed the result of the survey about calibration of Live Gas Flow Rate which was made to Mass Flow Manufactures.
- However, how to perceive the questions was different by the manufacturers.
- SG decided to resurvey focusing on the item which could be candidates to be standardized.
- On the basis of the result of the survey, SG will discuss it should be standardized or it should be solved by the other methods.

Action Item: SG to resurvey about calibration of Live Gas Flow Rate will be made to Mass Flow Manufacturers, focusing on the item which could be candidates to be standardized.

Action Item: SG to ask some comments and opinions to be standardized the specific heat value to NA Gas Specification TF and Europe Gases & Liquid Chemicals Committee.

8 Old Business

8.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

 Table 7 Previous Meeting Actions Items

Item #	Assigned to	Details	
G+F130628-01		To prepare for a small workshop / an enlarged committee meeting regarding the measurement of the small particles in the gas components and systems at SEMICON Ja 2013 (December 5).	
		• Invite some speakers from a device manufacturer, a measurement equipment manufacturer or a University Close (Workshop was held followed by this committee meeting conducted by H. Enami)	
G+F130927-01	SEMI Staff	To prepare SNARF and SEMI F80 Reapproval ballot for Cycle 1, 2014 Open	
G+F130927-02		To survey about calibration of Live Gas Flow Rate will be made to Mass Flow Manufacturers Close	

9 New Business

None

10 Action Item Review

10.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

11 Next Meeting and Adjournment

The next meeting of the Japan Gases & Facilities Committee is scheduled for Friday, April 4, 2014, 15:00-17:00, at SEMI Japan, Tokyo, Japan.

Prior to the Committee meeting, SG will be held on the same day.





Respectfully submitted by: Naoko Tejima Manager, Standards SEMI Japan Phone: +81.3.3222.5804 Email: ntejima@semi.org

Minutes approved by:

Hiromichi Enami (Hitachi High Technologies), Co-chairs	January 24, 2014
Isao Suzuki (MKS Japan), Co-chairs	January 24, 2014

Table 8 Index of Available Attachments #1

#	Title	
1	JA_G+F_Previous_Mtg_Minutes_131204	
2	SEMI_Staff_Report_131204	
3	NA_Facilities_and_Gases_Comm_Report_131204	
4	EU_Gases_&_Liquid_Chemicals_Report_131204	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.